

L Number	Hits	Search Text	DB	Time stamp
1	1	5278634.pn.	USPAT; EPO; JPO	2004/02/04 15:07
2	0	06-209885	USPAT; EPO; JPO	2004/02/04 15:08
3	1	"0878882"	USPAT; EPO; JPO	2004/02/04 15:09
4	0	(ASAI with KOUICHI with OE with KUNIO with NIIMURA with MASAYUKI).in.	USPAT; EPO; JPO	2004/02/04 15:10
5	9	(ASAI with KOUICHI and OE with KUNIO and NIIMURA with MASAYUKI).in.	USPAT; EPO; JPO	2004/02/04 15:13
6	0	8078882.URPN.	USPAT	2004/02/04 15:13
7	1	(CIRCUIT with BOARD with TRANSFER with APPARATUS).ti. and asai.in.	USPAT; EPO; JPO	2004/02/04 15:19
8	9	asai.in. and reference\$1mark with image	USPAT; EPO; JPO	2004/02/04 17:39
14	12	356/\$.ccls. and 29/\$.ccls. and rotat\$3 and camera same image same (reference mark)	USPAT; EPO; JPO	2004/02/04 17:42
15	541	356/\$.ccls. and detect\$3 with position and rotat\$3 and camera same image same (reference mark)	USPAT; EPO; JPO	2004/02/04 17:46
16	500	(356/\$.ccls. and detect\$3 with position and rotat\$3 and camera same image same (reference mark)) and process\$3	USPAT; EPO; JPO	2004/02/04 17:43
17	202	((356/\$.ccls. and detect\$3 with position and rotat\$3 and camera same image same (reference mark)) and process\$3) and (calibrat\$4 gaug\$3)	USPAT; EPO; JPO	2004/02/04 17:44
18	120	((356/\$.ccls. and detect\$3 with position and rotat\$3 and camera same image same (reference mark)) and process\$3) and (calibrat\$4 gaug\$3)) and rotat\$3 with axis	USPAT; EPO; JPO	2004/02/04 17:45
19	21	((356/\$.ccls. and detect\$3 with position and rotat\$3 and camera same image same (reference mark)) and process\$3) and (calibrat\$4 gaug\$3)) and rotat\$3 with axis) and mounting with system	USPAT; EPO; JPO	2004/02/04 17:45
23	2	901/\$.ccls. and detect\$3 with position and rotat\$3 and camera same image same (reference mark) and mounting with system and process\$3	USPAT; EPO; JPO	2004/02/04 17:48
24	4	414/\$.ccls. and detect\$3 with position and rotat\$3 and camera same image same (reference mark) and mounting with system and process\$3	USPAT; EPO; JPO	2004/02/04 17:49
25	0	264/\$.ccls. and detect\$3 with position and rotat\$3 and camera same image same (reference mark) and mounting with system and process\$3	USPAT; EPO; JPO	2004/02/04 17:49
-	14	mount\$3 with system.ti. and takeyoshi.in.	USPAT; US-PGPUB; EPO; JPO	2003/11/07 18:22
-	0	1117286.URPN.	USPAT	2004/01/30 16:25
-	1	4680523.pn.	USPAT; EPO; JPO	2004/01/30 16:25
-	1	4833776.pn.	USPAT; EPO; JPO	2004/01/30 16:27
-	2091	detect\$3 with posit\$3 and rotat\$3 same nozzle and axis	USPAT; EPO; JPO	2004/01/30 16:35
-	215	(detect\$3 with posit\$3 and rotat\$3 same nozzle and axis) and (image camera) and circuit with (board substrate)	USPAT; EPO; JPO	2004/01/30 16:37
-	203	((detect\$3 with posit\$3 and rotat\$3 same nozzle and axis) and (image camera) and circuit with (board substrate)) and mount\$3	USPAT; EPO; JPO	2004/01/30 17:16
-	2	"01183891"	USPAT; EPO; JPO	2004/01/30 17:16
-	2	"04372199"	USPAT; EPO; JPO	2004/01/30 18:02

-	13	4372199.URPN.	USPAT	2004/01/30 17:17
-	4	suction adj nozzle and detect\$3 with position and rotat\$3 with axis and imag\$3 and calibrat\$4	USPAT; EPO; JPO	2004/01/30 18:05
-	6	suction adj nozzle and detect\$3 with position and rotat\$3 and imag\$3 and calibrat\$4	USPAT; EPO; JPO	2004/01/30 18:07
-	843	reference adj point and detect\$3 with position and rotat\$3 and imag\$3 and calibrat\$4	USPAT; EPO; JPO	2004/01/30 18:07
-	6	reference adj point and detect\$3 with position and rotat\$3 and imag\$3 and calibrat\$4 with gauge	USPAT; EPO; JPO	2004/01/30 18:09
-	814	reference adj point and detect\$3 with position and rotat\$3 and imag\$3 and calibrat\$4 and process\$3	USPAT; EPO; JPO	2004/01/30 18:12
-	107	(reference adj point and detect\$3 with position and rotat\$3 and imag\$3 and calibrat\$4 and process\$3) and fiducial	USPAT; EPO; JPO	2004/01/30 18:16
-	51	((reference adj point and detect\$3 with position and rotat\$3 and imag\$3 and calibrat\$4 and process\$3) and fiducial) and mounting	USPAT; EPO; JPO	2004/01/30 18:19
-	46	(reference adj point and detect\$3 with position and rotat\$3 and imag\$3 and calibrat\$4 and process\$3) and nozzle	USPAT; EPO; JPO	2004/01/30 18:38
-	2995	detect\$3 with position and rotat\$3 with axis and mounting with (component device)	USPAT; EPO; JPO	2004/01/30 18:40
-	259	29/\$.ccls. and (detect\$3 with position and rotat\$3 with axis and mounting with (component device))	USPAT; EPO; JPO	2004/01/30 18:40
-	52	(29/\$.ccls. and (detect\$3 with position and rotat\$3 with axis and mounting with (component device))) and (imag\$3 camera) and mark	USPAT; EPO; JPO	2004/01/30 18:45
-	44	(29/\$.ccls. and (detect\$3 with position and rotat\$3 with axis and mounting with (component device))) and (imag\$3 camera) and (reference fiducial) with (point mark)	USPAT; EPO; JPO	2004/01/30 18:42
-	17	(29/\$.ccls. and (detect\$3 with position and rotat\$3 with axis and mounting with (component device))) and calibrat\$4	USPAT; EPO; JPO	2004/01/30 18:45
-	9	5758410.URPN.	USPAT	2004/02/02 17:56
-	994	mounting with rotat\$4 and lower\$4 and camera with imag\$4 and process\$3	USPAT; EPO; JPO	2004/02/02 18:29
-	98	(mounting with rotat\$4 and lower\$4 and camera with imag\$4 and process\$3) and 29/\$.ccls.	USPAT; EPO; JPO	2004/02/02 18:29
-	80	((mounting with rotat\$4 and lower\$4 and camera with imag\$4 and process\$3) and 29/\$.ccls.) and angle	USPAT; EPO; JPO	2004/02/02 18:30
-	2547	rotat\$3 with axis and mounting and (image camera) and lowering	USPAT; EPO; JPO	2004/02/03 18:44
-	1770	(rotat\$3 with axis and mounting and (image camera) and lowering) and process\$3	USPAT; EPO; JPO	2004/02/03 18:45
-	648	((rotat\$3 with axis and mounting and (image camera) and lowering) and process\$3) and position with detect\$3	USPAT; EPO; JPO	2004/02/03 18:45
-	209	((rotat\$3 with axis and mounting and (image camera) and lowering) and process\$3) and position with detect\$3) and vacuum	USPAT; EPO; JPO	2004/02/03 18:46
-	165	((((rotat\$3 with axis and mounting and (image camera) and lowering) and process\$3) and position with detect\$3) and vacuum) and (circuit substrate)	USPAT; EPO; JPO	2004/02/03 18:46
-	161	(((((rotat\$3 with axis and mounting and (image camera) and lowering) and process\$3) and position with detect\$3) and vacuum) and (circuit substrate)) and (reference mark)	USPAT; EPO; JPO	2004/02/03 18:47